

sheet bonded to the walls; nozzles respectively communicating with the channels and a transverse duct for supplying droplet fluid to the channels; a defining surface of said transverse duct having an array of parallel conductive tracks thereon spaced at intervals corresponding with the channel spacing, each track being electrically connected to said electrodes; said defining surface comprising a glass or ceramic other than said piezoelectric ~~ceramic~~ ^{material}.

76. Apparatus as claimed in claim 75, wherein said glass or ceramic has a relatively high elastic modulus compared with that of the piezoelectric material.

77. Apparatus as claimed in claim 76, wherein said glass or ceramic has an expansion coefficient matched to that of <110> silicon.

78. Apparatus as claimed in claim 77, wherein said glass or ceramic is borosilicate glass.

79. Apparatus as claimed in claim ⁷⁵~~20~~, wherein said layer of piezoelectric material is poled normal ^{to the base sheet} ~~thereto~~.

80. Apparatus as claimed in claim ⁷⁵~~20~~, wherein said electrodes are formed on channel-facing surfaces of the walls.